## Amendm nts to the Claims

Claims 1-33 (Cancelled).

34. (Currently amended) A bit line contact comprising:

a layer formed on a substrate and including an opening extending through the layer to a node on the substrate;

a first dielectric sidewall <u>spacer</u> formed in the <u>an</u> opening and coating an interior sidewall of the opening, the opening extending to a node on a substrate;

a second dielectric sidewall <u>spacer</u> formed in the opening and coating an interior sidewall of the first dielectric <u>layer sidewall spacer</u>; and

a conductive plug formed within an interior sidewall of the second dielectric layer sidewall spacer and extending through the opening to the node.

- 35. (Currently amended) The bit line contact of claim 34, wherein the first dielectric sidewall <u>spacer</u> is formed of a first material and the second dielectric sidewall <u>spacer</u> is formed of a second material having a lower relative dielectric constant than the first dielectric sidewall <u>spacer</u>.
- 36. (Original) The bit line contact of claim 34, wherein the conductive plug comprises doped polysilicon.

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- 37. (Original) The bit line contact of claim 34, wherein the contact is laterally surrounded by six capacitors.
- 38. (Currently amended) The bit line contact of claim 34, wherein the first dielectric sidewall <u>spacer</u> has an aspect ratio of twenty five or more.
- 39. (Currently amended) The bit line contact of claim 34, wherein the first dielectric sidewall <u>spacer</u> comprises silicon nitride.
- 40. (Currently amended) The bit line contact of claim 34, wherein the second dielectric sidewall <u>spacer</u> comprises silicon dioxide.
- 41. (Currently amended) The bit line contact of claim 34, wherein the second dielectric sidewall <u>spacer</u> is thicker than the first dielectric sidewall <u>spacer</u>.